PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Yongjun Hu

Serial No.: 10/771,828

Filed: February 4, 2004

For: PROCESS FOR FORMING A
DIFFUSION BARRIER MATERIAL
NITRIDE FILM

Confirmation No.: 3960

Examiner: Q Hoang

Group Art Unit: 2818

Attorney Docket No.: 2269-6983.5US
(96-0790.05/US)

NOTICE OF EXPRESS MAILING

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SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Mail Stop RCE
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P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In compliance with the duty to disclose information material to patentability pursuant to 37 C.F.R. § 1.56, it is respectfully requested that this Supplemental Information Disclosure Statement be entered and the document listed on attached Form PTO-1449 or PTO/SB/08 be considered by the Examiner and made of record. A copy of the listed document is enclosed pursuant to 37 C.F.R. § 1.98(a).

In accordance with 37 C.F.R. § 1.97(g) and (h), filing of this Supplemental Information Disclosure Statement is not to be construed as a representation that a search has been made or an

admission that the information cited herein is, or is considered to be, material to patentability as defined in 37 C.F.R. § 1.56(b). Further, no representation is made by Applicant herein that no other possible material information as defined in 37 C.F.R. § 1.56 (b) exists.
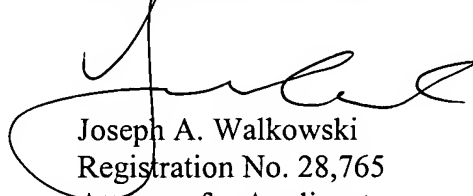
Other Documents

WOLF, S., "Silicon Processing for the VLSI Era," Vol. 2, Lattice Press, 1990, pp. 147-150.

Applicant offers to supply any explanation or discussion of the document which the Examiner feels is necessary or desirable and which is requested.

This Supplemental Information Disclosure Statement is filed concurrently with an RCE in the above-identified application, and therefore no additional fee is due.

Respectfully submitted,

Joseph A. Walkowski
Registration No. 28,765
Attorney for Applicant
TRASKBRITT
P.O. Box 2550
Salt Lake City, Utah 84110-2550
Telephone: 801-532-1922

Date: September 12, 2005
JAW/dlm:slm
Enclosures: Form PTO-1449 or PTO/SB/08
Copy of documents cited

Document in ProLaw

Substitute for form 1449A/PTO

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(use as many sheets as necessary)

Complete if Known	
Application Number	10/771,828
Filing Date	February 4, 2004
First Named Inventor	Yongjun Hu
Group Art Unit	2818
Examiner Name	Q Hoang
Attorney Docket Number	2269-6983.5US (96-0790.05/US)

Sheet | 1 | of | 1

NON PATENT LITERATURE DOCUMENTS

Examiner Initials *	Cite No.[1]	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T[2]
		WOLF, S., "Silicon Processing for the VLSI Era," Vol. 2, Lattice Press, 1990, pp. 147-150.	

Examiner Signature		Date Considered	

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